



IFW #

PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:

AXEL PREUSSE  
MARKUS NOPPER  
HOLGER SCHÜHRER

Examiner: Edward J. Wojciechowicz

Group Art Unit: 2815

Serial No.: 10/747,722

Att'y Docket: 2000.109700/DE0351

Filed: December 29, 2003

Customer No.: 23720

For: METHOD OF REDUCING WAFER  
CONTAMINATION BY REMOVING  
UNDER-METAL LAYERS AT THE  
WAFER EDGE

**RESPONSE TO OFFICE ACTION DATED NOVEMBER 3, 2004**

Mail Stop Amendment  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

CERTIFICATE OF MAILING 37 C.F.R. 1.8	
I hereby certify that this correspondence is being deposited with the U.S. Postal Service with sufficient postage as First Class Mail in an envelope addressed to: Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450, on the date below:	
November 19, 2004 Date	<i>Mary Paul</i> Signature

This paper is submitted in response to the Office Action dated November 3, 2004, for which the three-month date for response is February 3, 2005.

A fee in the amount of \$160.00 is believed to be due in connection with the present paper. **The Director is authorized to deduct such fee, and any other fees required under 37 C.F.R. §§ 1.16 to 1.21, from the Advanced Micro Devices, Inc. Deposit Account No. 01-0365/DE0351.** In the event the monies in that account are insufficient, the Director is authorized to withdraw funds from Williams, Morgan & Amerson, P.C. Deposit Account No. 50-0786/2000.109700.

Reconsideration of the application in view of the following amendments and remarks is respectfully requested.